

# caeleste



Space and scientific CMOS  
image sensors workshop  
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## High dynamic range CIS with true global shutter and charge domain binning

A. Kalgi<sup>1</sup>, B. Sezgin<sup>1</sup>, D. Gautam<sup>1</sup>, A. Hoorebeeck<sup>1</sup>, B. Dierickx<sup>1</sup>, Y. Creten<sup>1</sup>, K. Minoglou<sup>2</sup>

<sup>1</sup>Caeleste, Mechelen, Belgium

<sup>2</sup>ESA, ESTEC, The Netherlands

# Purpose

The “ELFIS2” image sensor features the combination of

1. BSI (Backside illumination)
  - High QE also at near infrared wavelength
2. TID and SEL/SEU radiation-hard design
3. “True”, Motion Artifact Free (MAF) **HDR** (High Dynamic Range)
  - ⇒ By reading the same photocharge on two different conversion capacitances
  - ⇒ All values over the full dynamic range have identical integration time and are synchronous
4. IWR Global shutter using “**GS**” CMOS technology, which
  - ⇒ Allows low noise readout using CDS (correlated double sampling)
  - ⇒ Enabling Global Shutter without dark current penalty

Nice to have

- Binning capabilities
  1. **Charge domain**
  2. Voltage domain

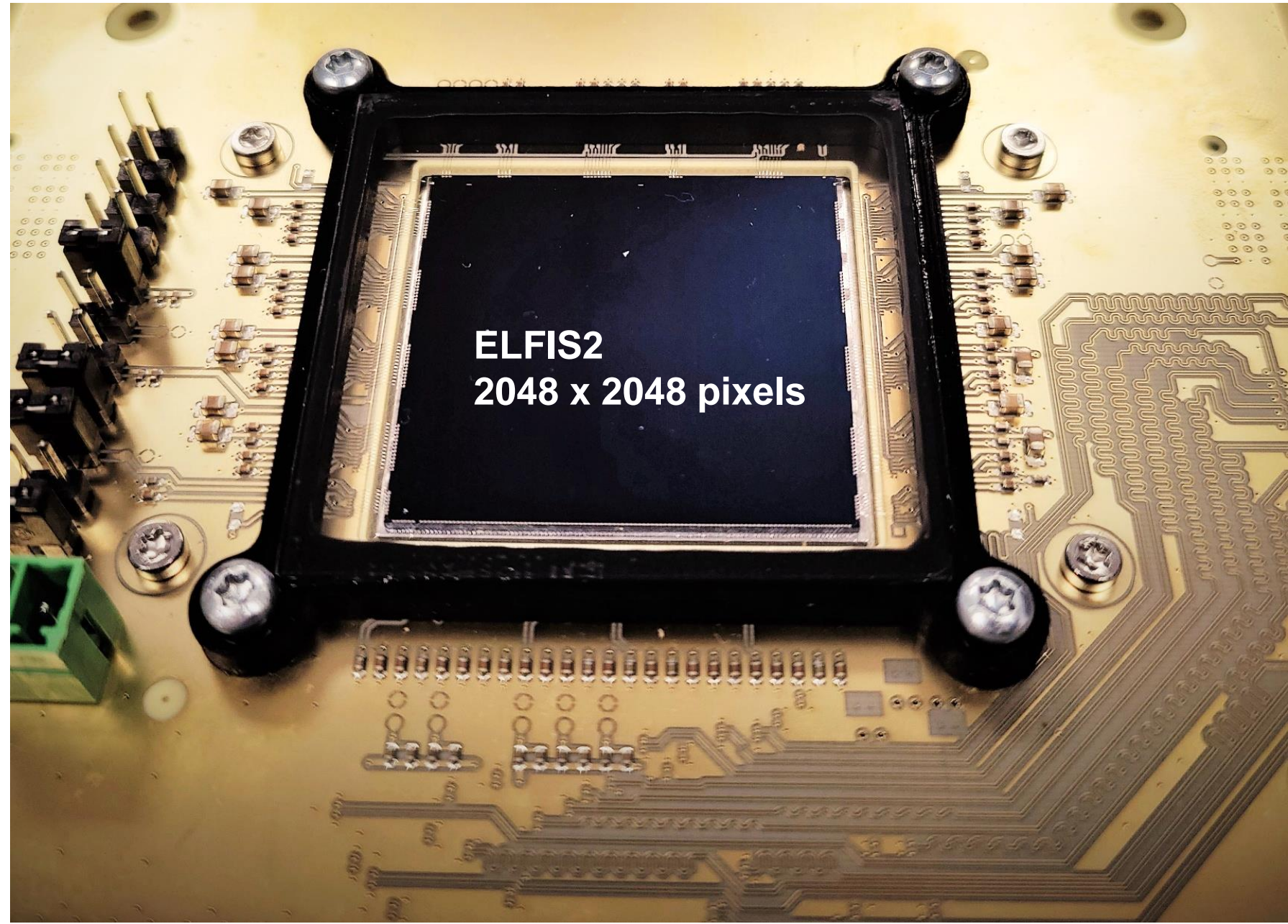
ELFIS2 is the successor of ELFIS

Dierickx & al, "A rad-hard, global shutter, true HDR, backside illuminated image sensor", Space & Scientific CMOS Image Sensors Workshop, Toulouse, 26-27 Nov 2019

# Outline

ELFIS2 assembled chip on board [CoB]

1. Purpose
2. Key specifications
3. Charge domain global shutter and HDR
  - Concept
  - Measurement results
4. Charge domain binning
  - Concept
  - Measurement results
5. QE
6. Conclusions



# Key specifications, measured

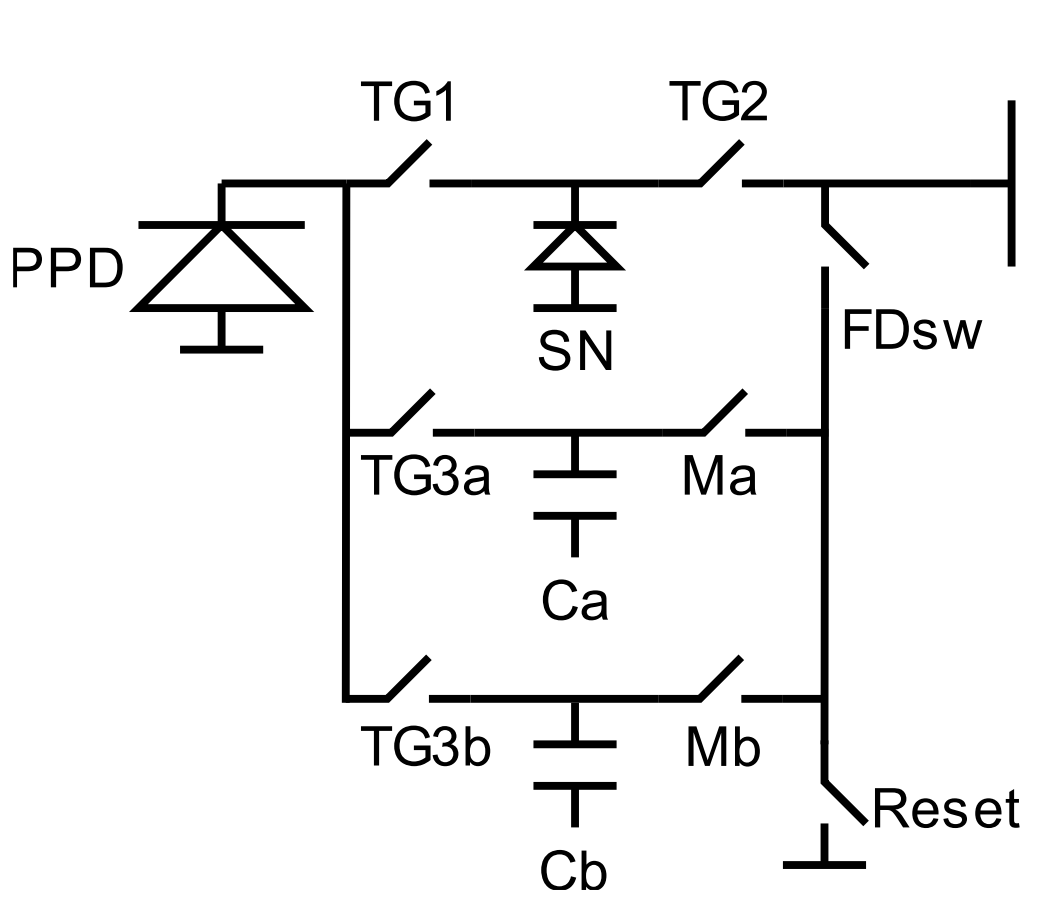
Stitching	✓
Stitch block size	1024 x 512
Possible resolutions	1024 x 512 <b>2048 x 2048</b> 9k x 9k
High gain Full well	13 ke <sup>-</sup>
Low gain Full well (IWR)	180 ke <sup>-</sup>
Low gain Full well (ITR)	360 ke <sup>-</sup>
ROI in Y	✓
Read noise at nominal speed, GS	3.5 e <sub>rms</sub>
FPN reduction	✓
Voltage domain binning	✓
Charge domain binning	✓
Low noise mode	✓

Back side illumination	✓
Backbias capability	✓
EPI thickness	6.5 μm, <b>12 μm</b> , <b>22 μm</b> HIRES
QE for 22μm epi	~80% @ 400 nm ~85% @ 540-700 nm ~30% @ 1000nm
MTF	0.52 [12μm epi]
PLS	1/4000 at 630 nm 1/600 at 830 nm
Image lag	<0.5%
PPD dark current	< 500 e <sup>-</sup> /s @ 33°C
Output channels for 2k*2k	16
Analog outputs	✓
Nominal channel rate	40 MHz
Frame rate for 2k*2k	150 fps

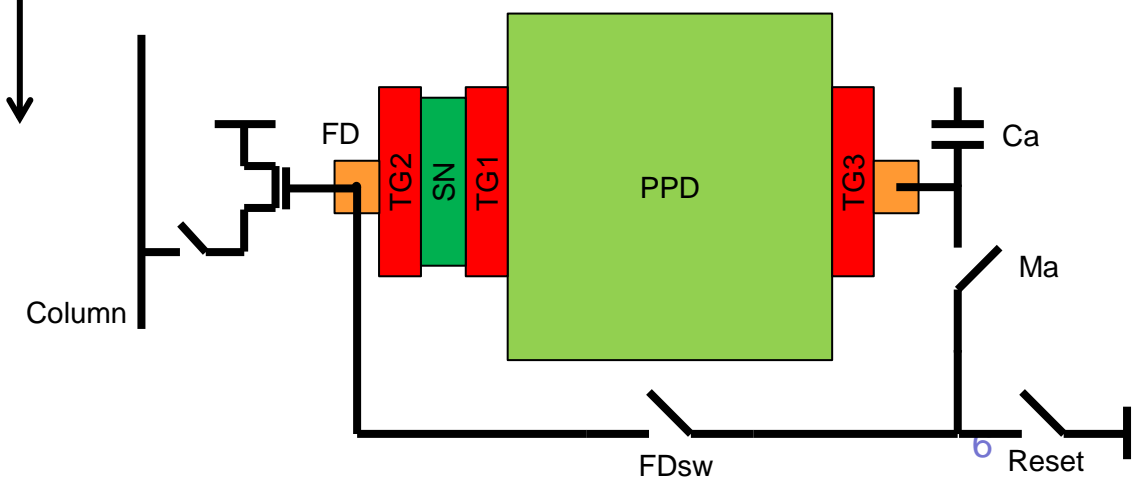
**3.**

## **Charge domain Global shutter and HDR**

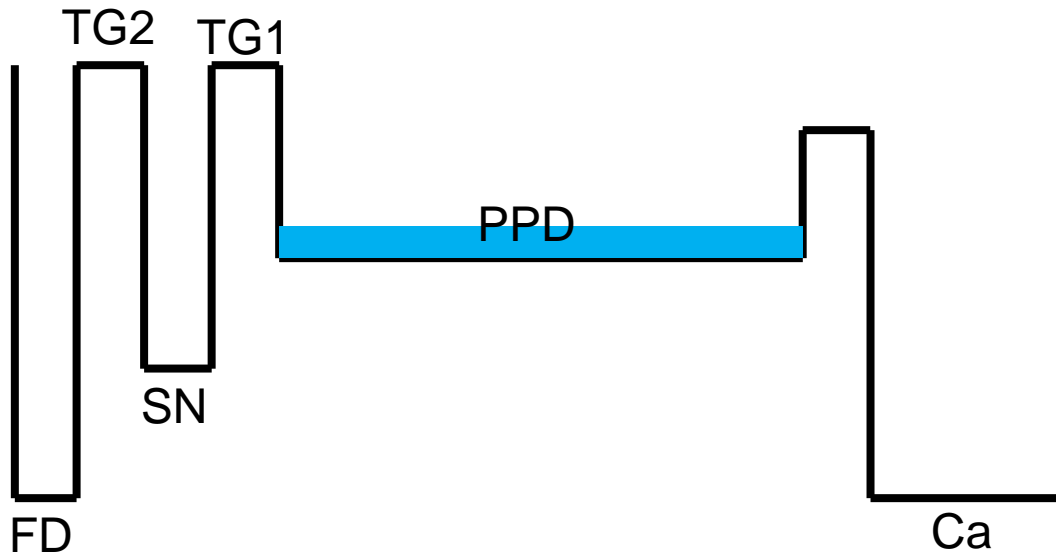
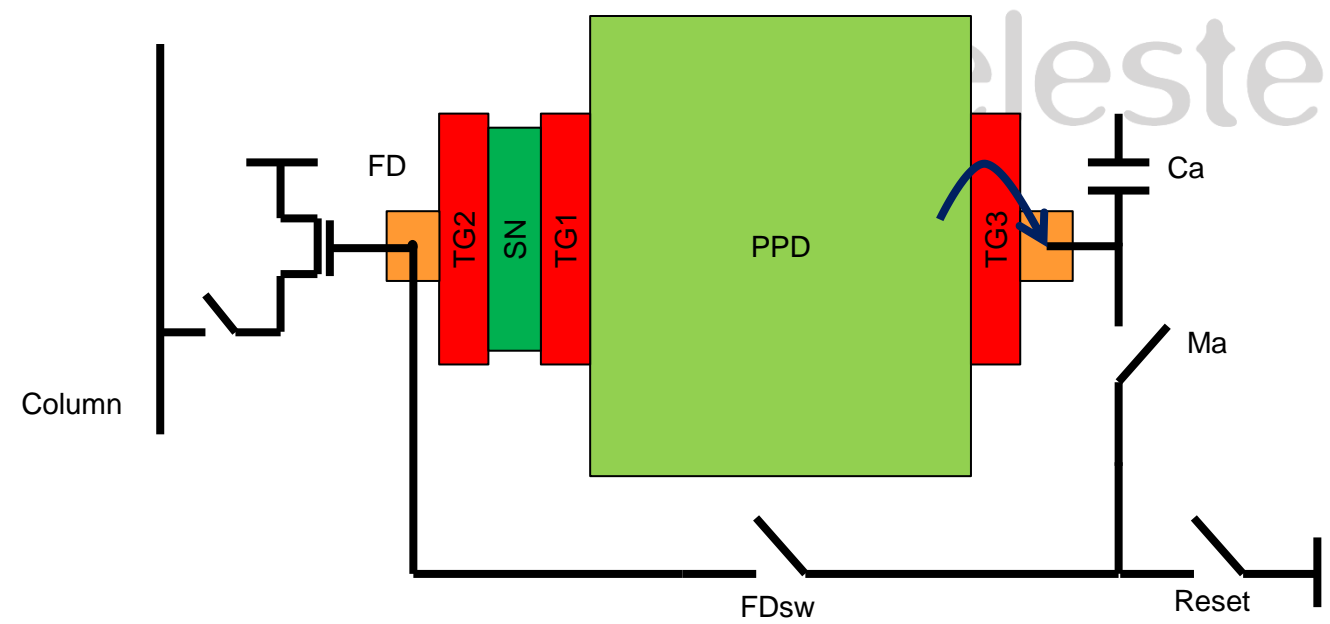
# Charge domain Global shutter and HDR



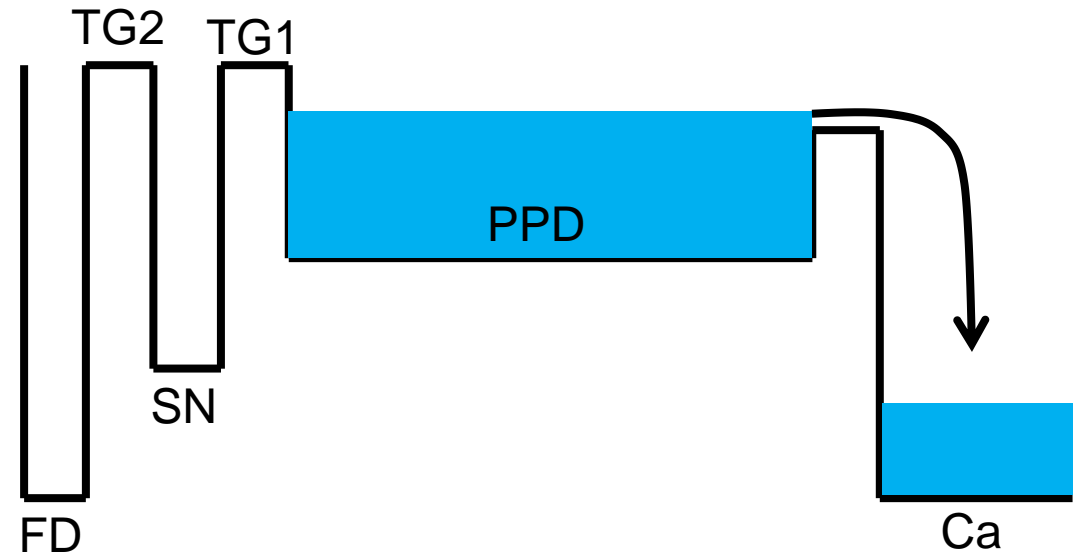
- During integration
  - charges overflow from PPD to Ca (or Cb) through TG3a (or TG3b)
- Global operations
  - PPD to SN through TG1
  - PPD to Ca through TG3a to transfer remaining charges
- Readout
  - High gain: SN to FD through TG2
  - Low gain: Averaging of FD and Ca



# During Integration

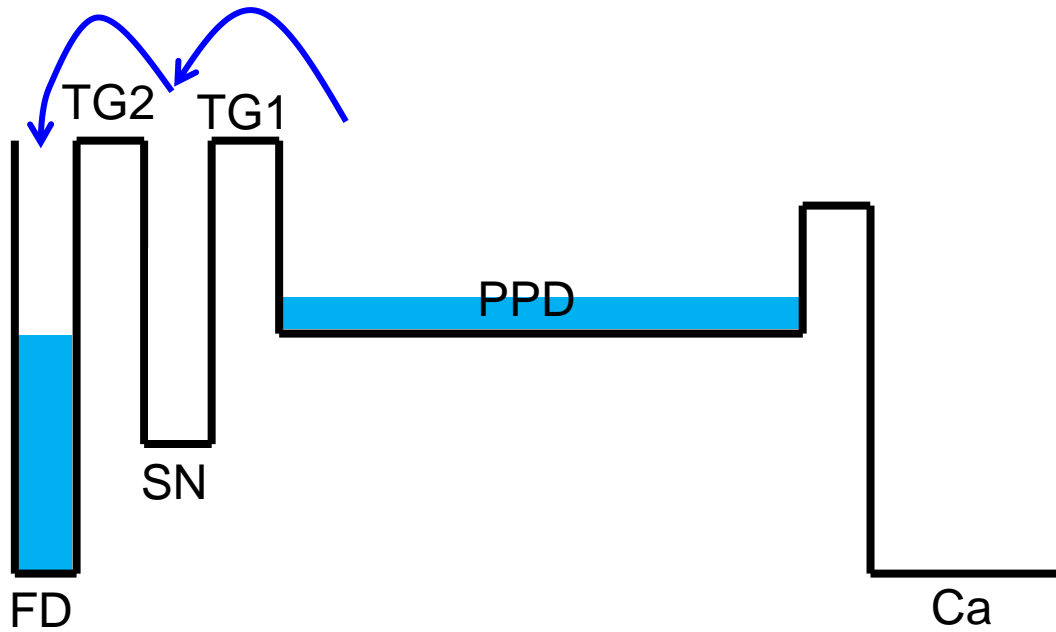
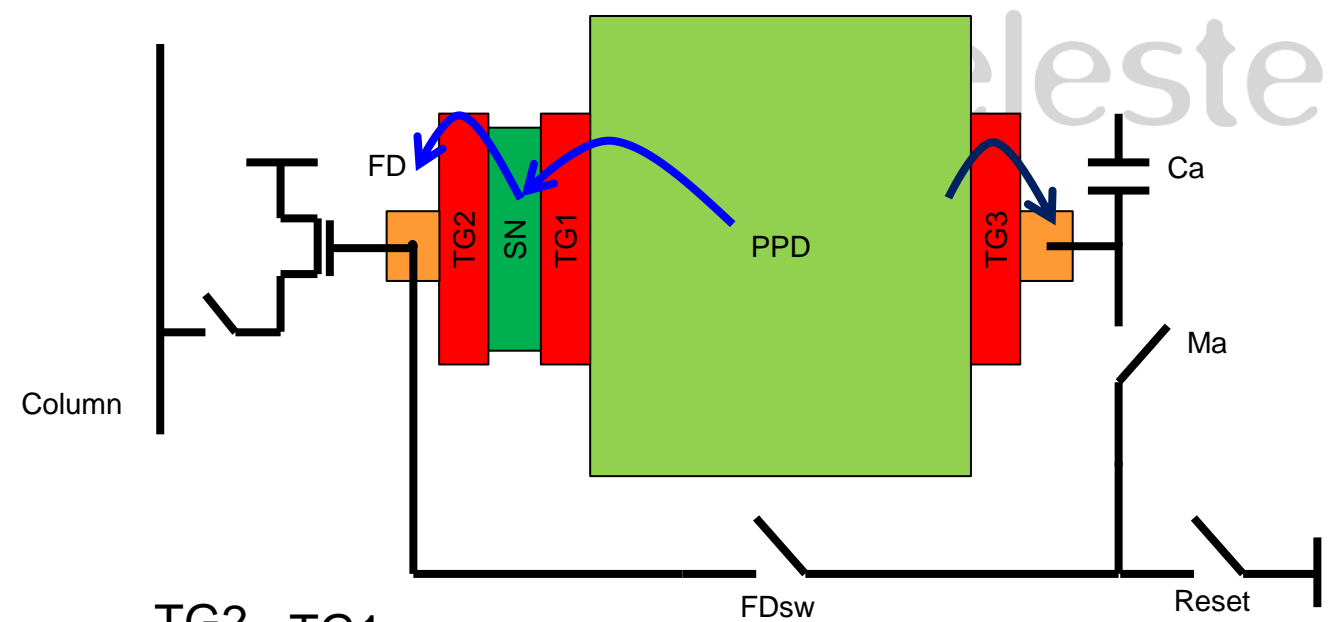


Low illumination:  
Charges are contained in PPD



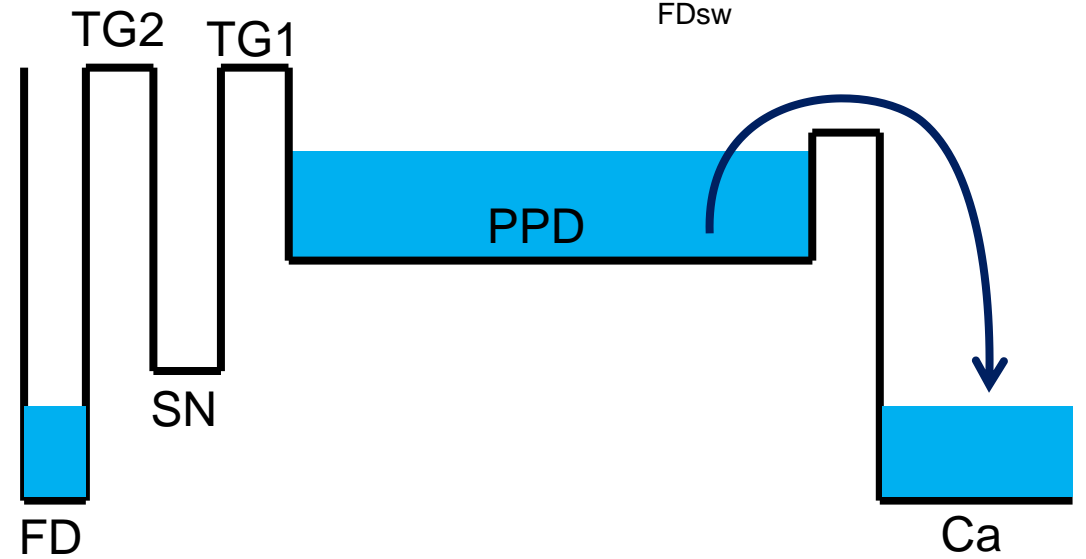
High illumination  
Charges overflow to extra capacitor Ca or Cb

# During Readout



Low illumination:

- High gain value after CDS is contains all information
- Ca is empty, low gain value is void.



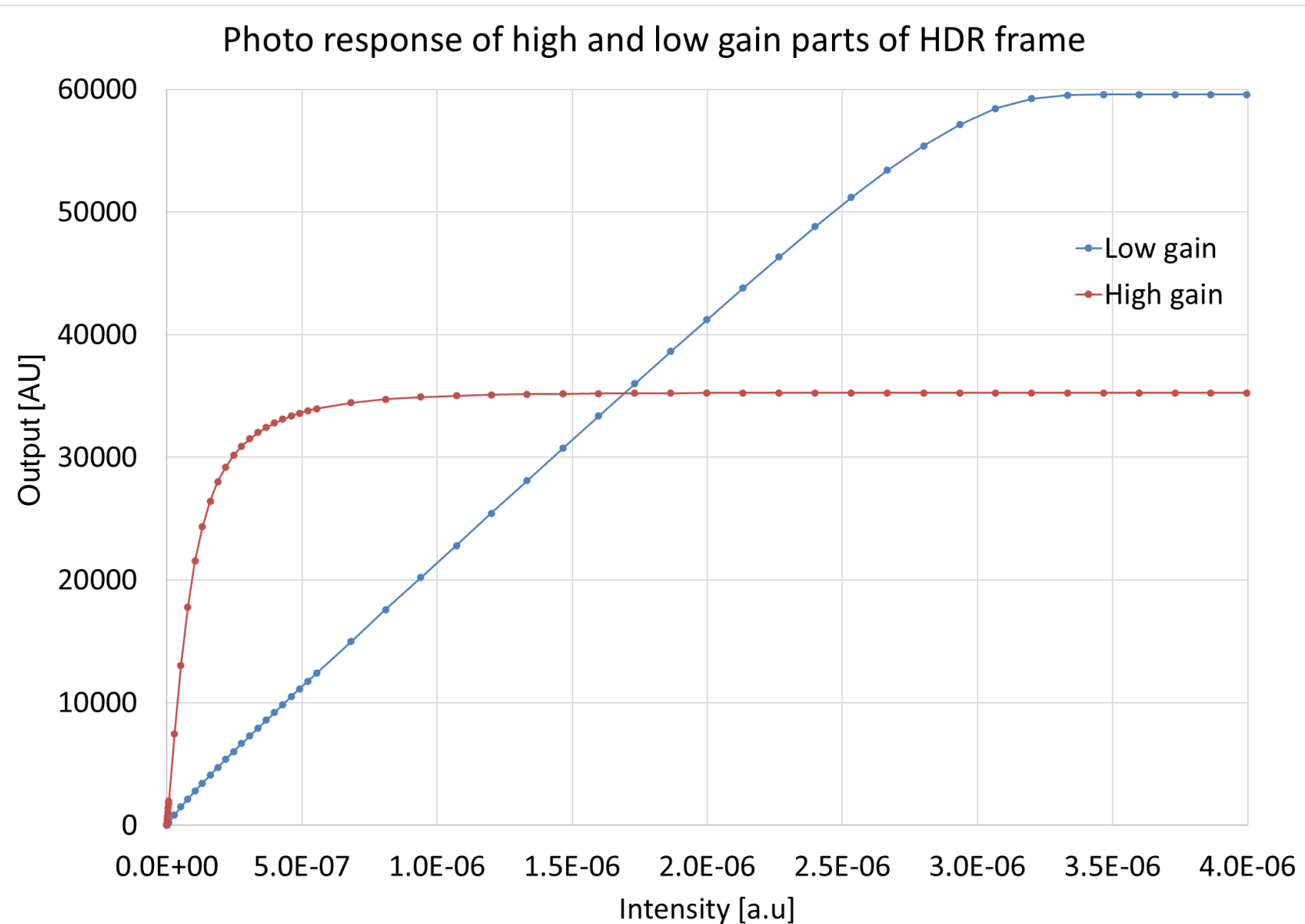
High illumination:

- High gain value saturates
- Low gain value is the sum of Ca and FD



# Measured Performance

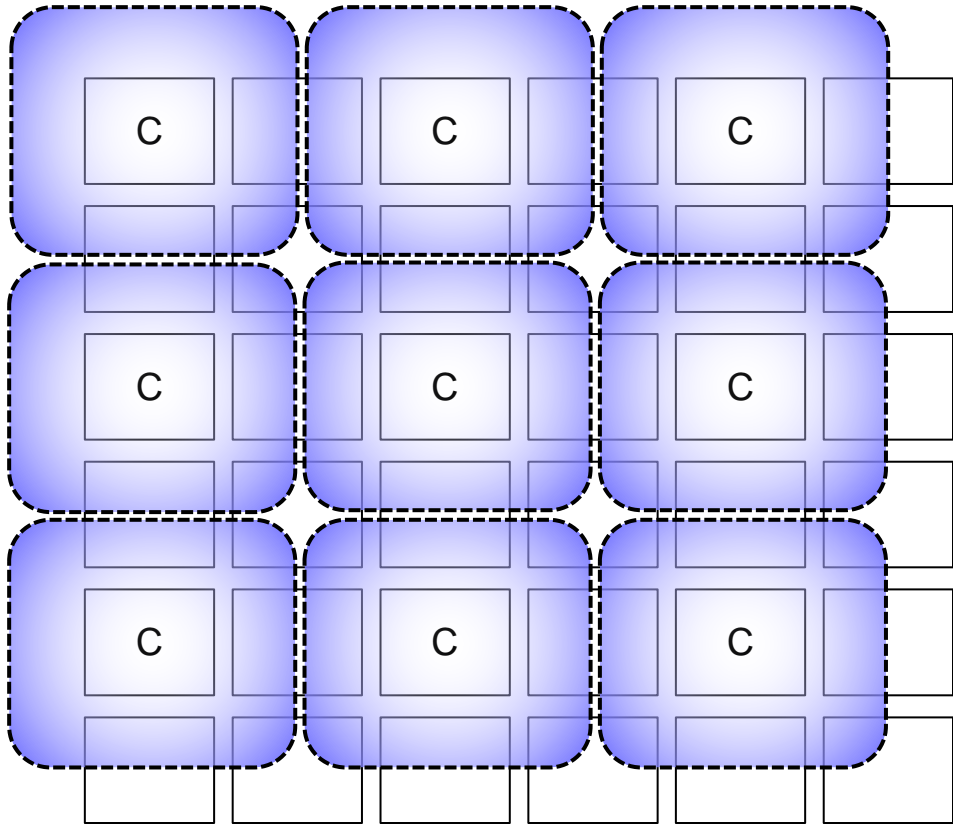
- High gain swing is limited by storage node capacity
- The overflow mechanism ensures high full well even with a PPD with low depletion voltage
- Obtaining HDR information
  - At low illumination levels, only high gain value is used
  - At high illumination only low gain information is used
  - The transition a weighted average of high gain and low gain values is used



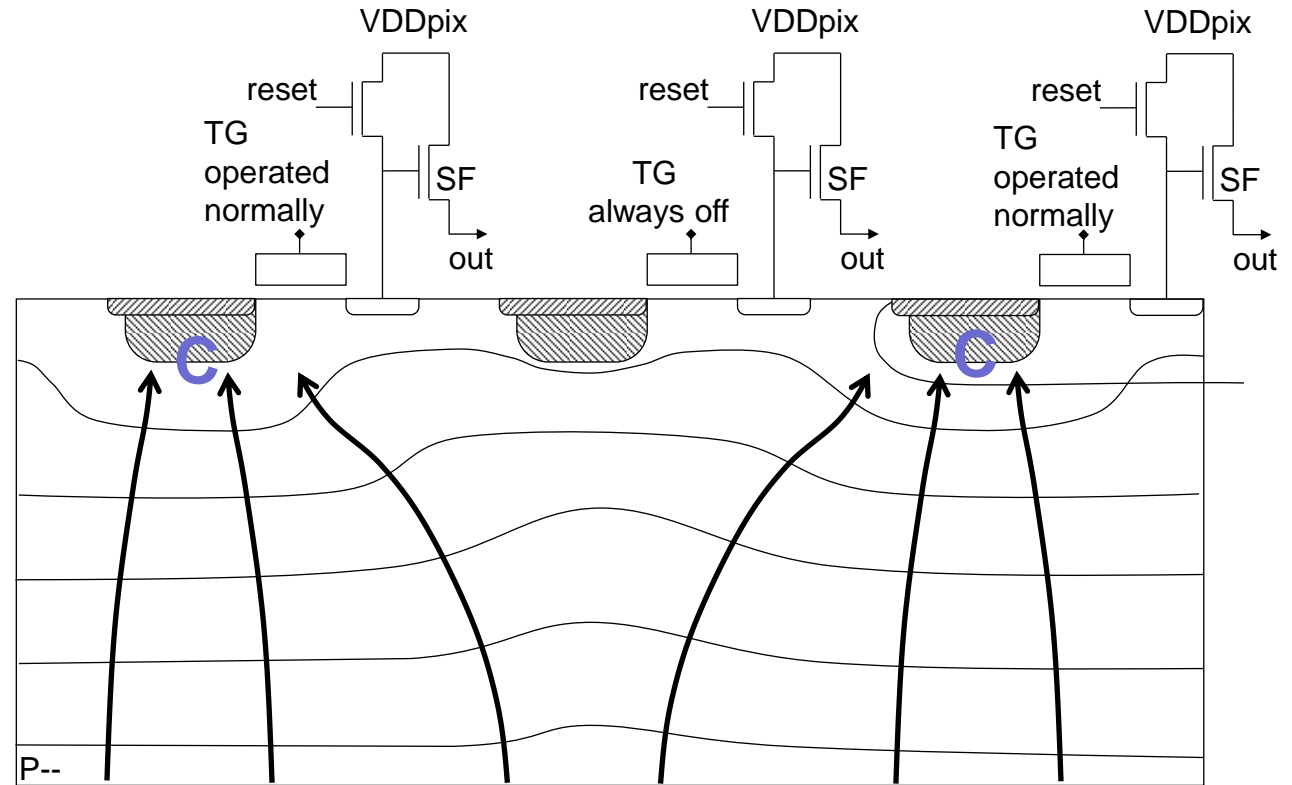
4.

## Charge domain binning

# Concept of Charge domain binning



- In 2x2 configuration Pixel 'C' is intended to collect charges
- Others are in non-integrating state



## Example implementation

- The center PPD is never reset and thus floating
- PPD evolves to a non-integrating state.

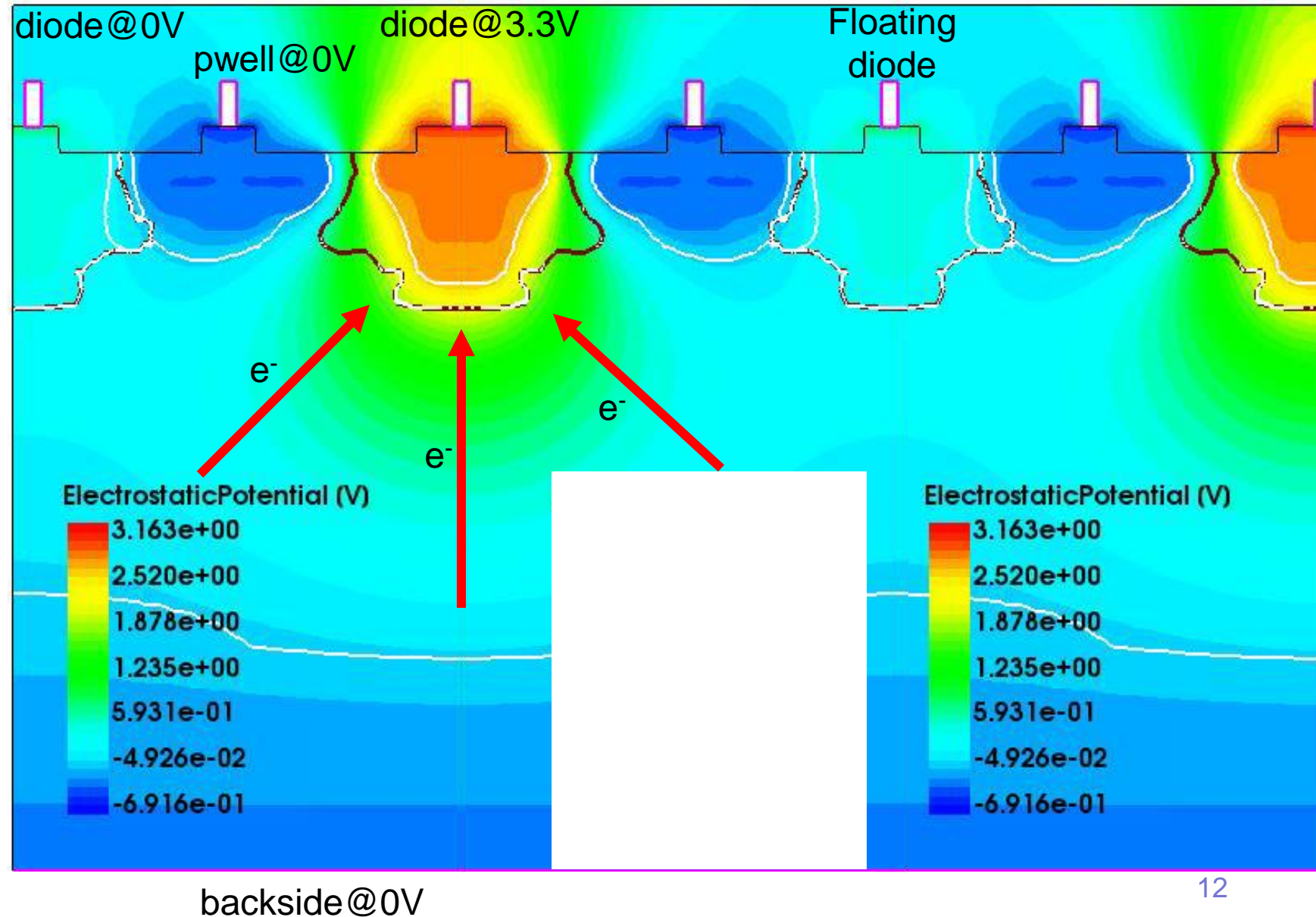
# TCAD Potential Profile, ideal case

- 12 $\mu\text{m}$  pitch
- 10 $\mu\text{m}$  thick HIRES epi (BSI)
- No backbias
- Illumination from backside
- Small diode (non PPD) @3.3V

Observe significant tilt of equipotential lines.  
 Almost complete collection of backside charges in central diode for this simulation case.

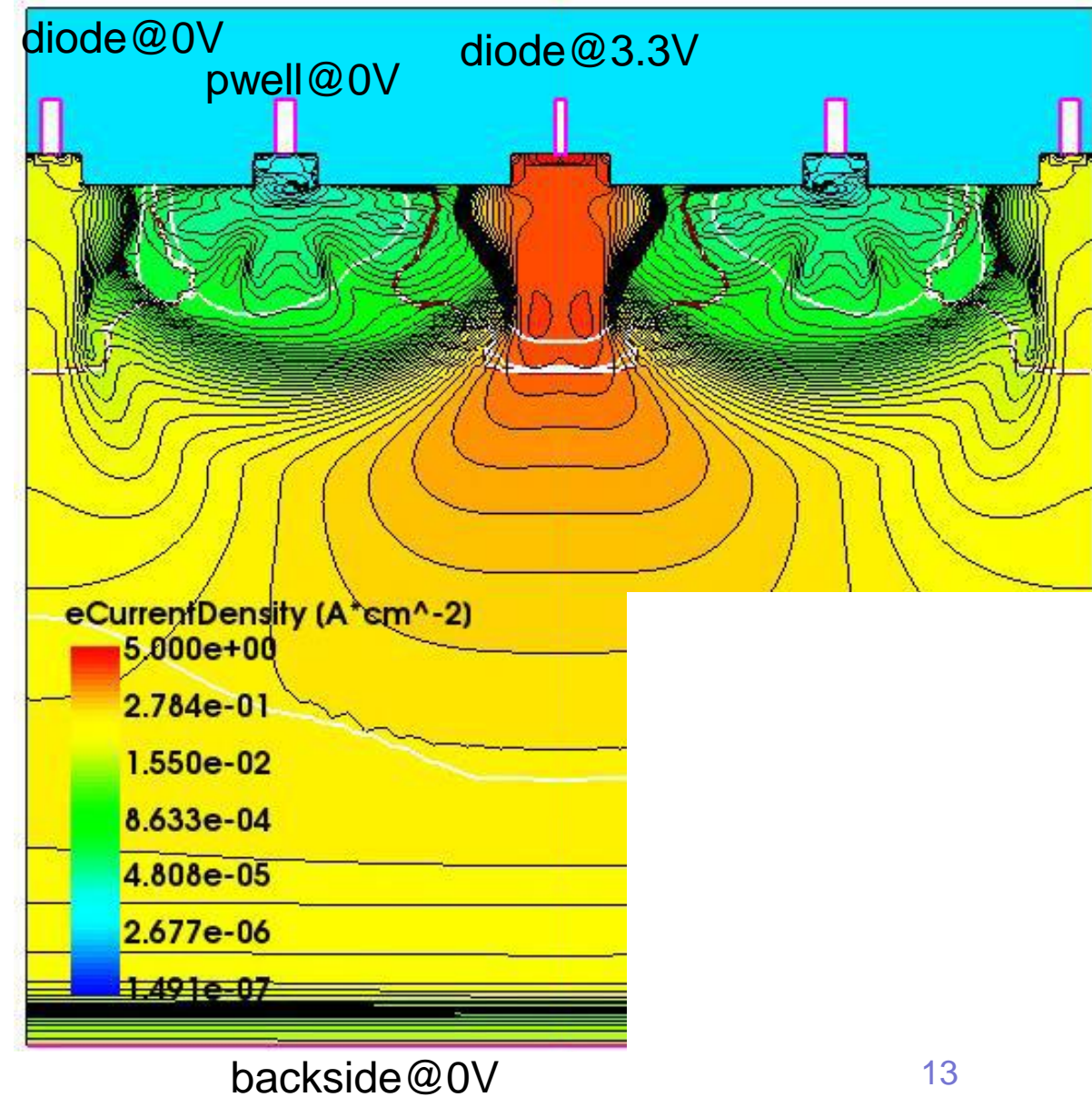
Actual situation differs

- Real PPD
- Biased PPD  $V_{\text{depletion}}$  is at +0.1V
- Floating diode is at -0.4V



# TCAD Current density, ideal case

- Current density is highest towards the diodes biased at 3.3V while the diodes at 0V have almost no current flowing into them.

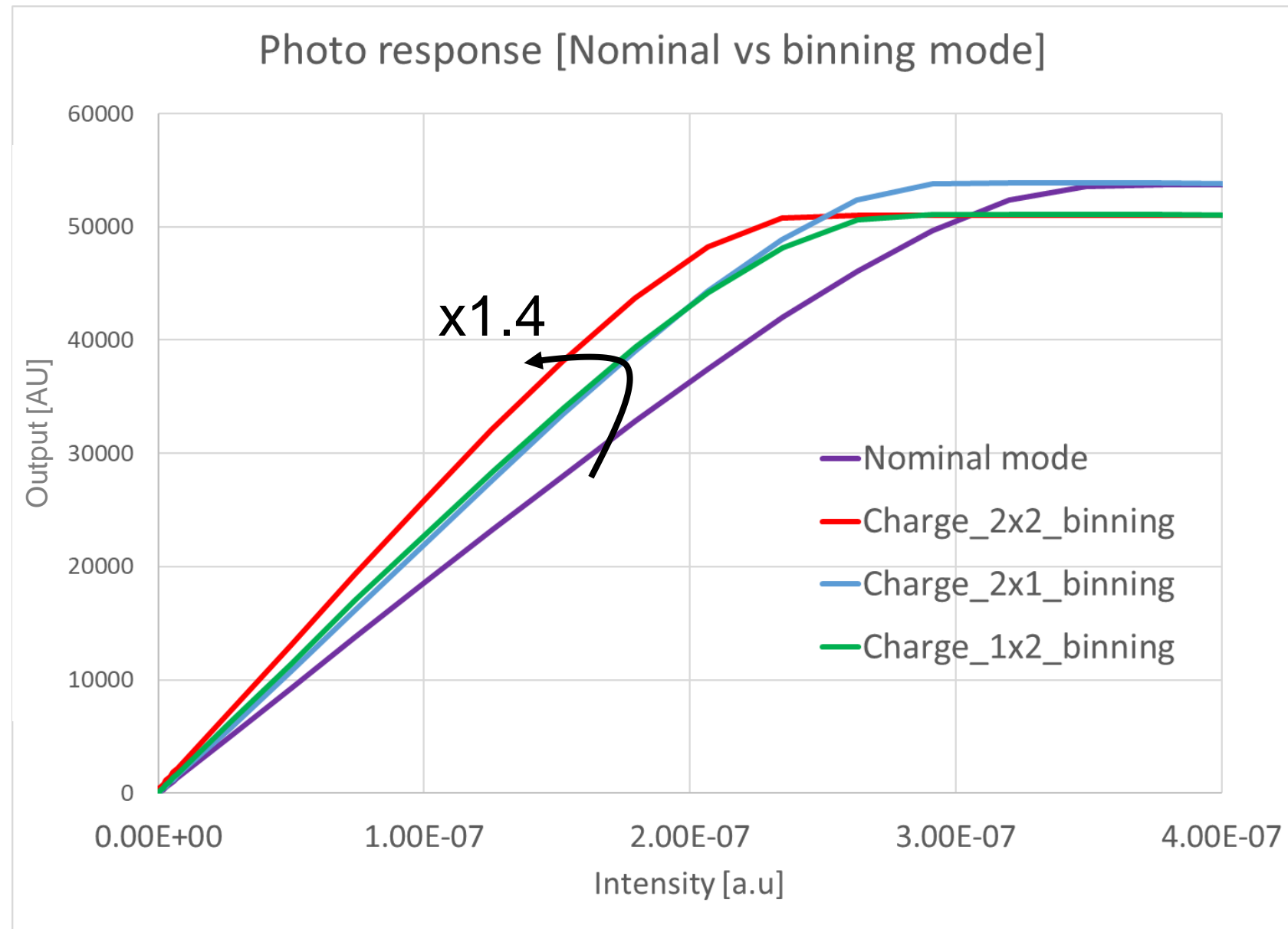


# Measured Performance

- Binning concept works
- Performance is much less pronounced than in ideal case
- Ideal: binning has 4x higher response than nominal (non binned)
- Actual: binning has 1.4 times higher response than nominal mode

## Reasons for reduced performance?

- ✓ Too small difference in potential between collecting and non-collecting diodes due to low depletion voltage. -0.4 V vs +0.1V.
- Recombination?
- Backside electric field distribution?

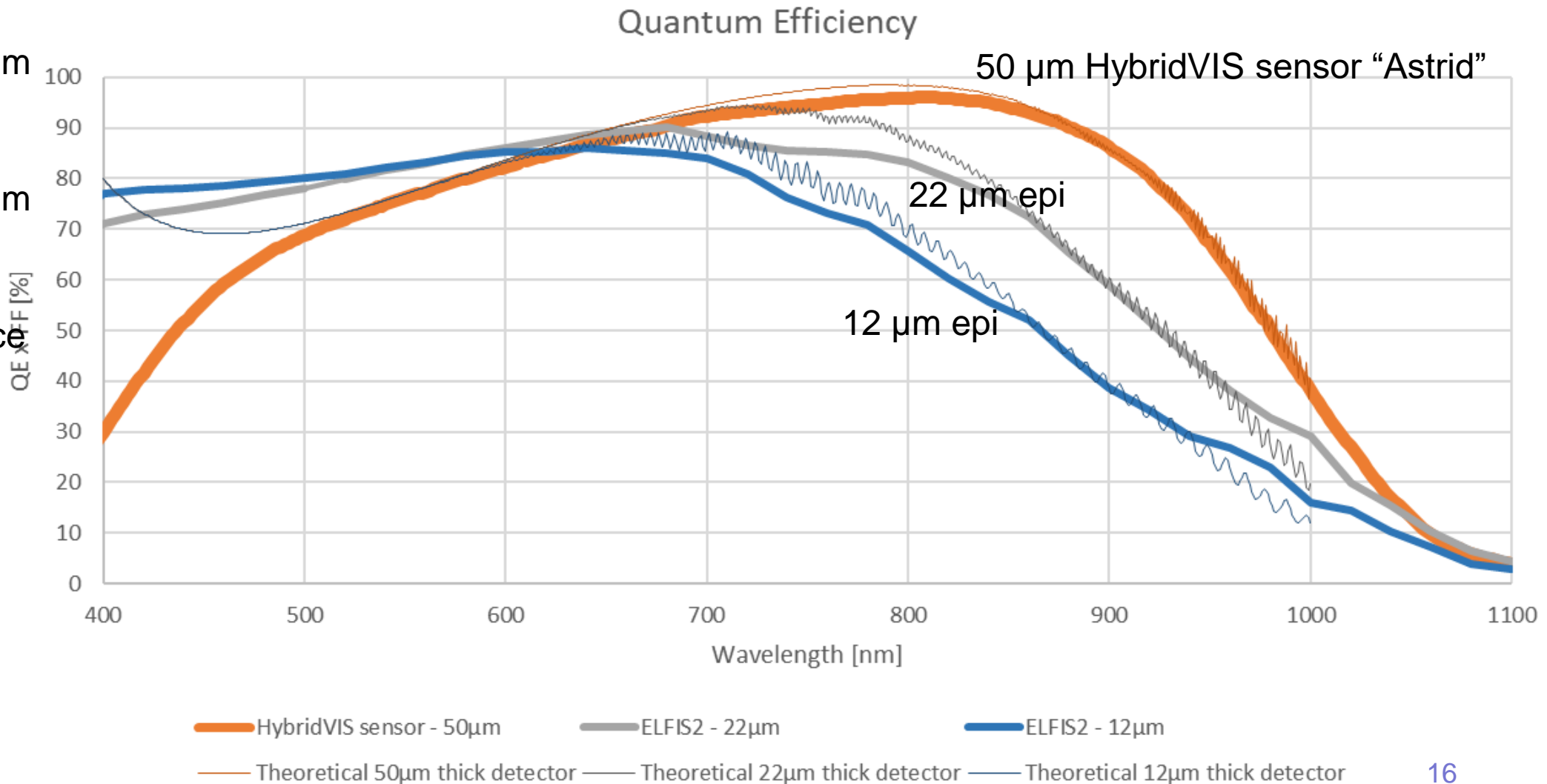


# 5. Quantum Efficiency

# Quantum Efficiency

- 58% QE at 900nm for 22 $\mu$ m epi
- 38% QE at 900nm for 12 $\mu$ m epi
- Close correspondence to model

Compare to ASTRID (HybridVIS, this workshop)





# 5. Conclusions

# Conclusions

- Functionality of the 2k x 2k ELFIS2 sensor demonstrated
  - True High dynamic range:  $360000e Q_{FW} / 3.5e Q_{noise} > 100dB$
  - Motion artifact free global shutter combined with HDR
- Concept of charge domain binning in CMOS first time demonstrated, yet with lower efficiency
  - Lower performance probably caused by a low voltage difference between collecting and floating PPDs
- Excellent QE with BSI on 22  $\mu m$  thick HIRES EPI wafer
  
- Further work
  - Behavior at Low temperatures
  - TID/SE radiation tests
  - Qualify low noise modes
  - On-chip FPN cancellation
  - Understand and improve charge domain binning